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				Application Number	10/576,342
				Filing Date	April 18, 2006
				First Named Inventor	DELATTRE, Cyril
				Art Unit	1641
				Examiner Name	LAM, Ann Y.
Sheet	1	of	1	Attorney Docket Number	10404.038.00

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
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NON PATENT LITERATURE DOCUMENTS				
Examiner Initials <sup>*</sup>	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>	
	CA	LEE, Junghoon, et al., Electrowetting And Electrowetting-On-Dielectric For Microscale Liquid Handling, <i>Sensors and Actuators A</i> 95 (2002), pp. 259-268.		
	CB	BRATTEN, Craig D. T., et al., Micromachining Sensors for Electrochemical Measurement in Subnanoliter Volumes, <i>Anal. Chem.</i> 1997, 69, pp. 253-258.		
	CC	YANG, Mengsu, et al. Covalent Immobilization of Oligonucleotides on Modified Glass/Silicon Surfaces for Solid-Phase DNA Hybridization and Amplification, <i>Chemistry Letters</i> 1998, pp.257-258.		
	CD	BONCHEVA, Mila, et al., Design of Oligonucleotide Arrays at Interfaces, <i>Langmuir</i> 1999, 15, pp. 4317-4320.		
	CE	JANSEN, Henri, et al., The Black Silicon Method: A Universal Method for Determining the Parameter Setting of a Fluorine-Based Reactive Ion Etcher In Deep Silicon Trench Etching With Profile Control, <i>J. Micromech, Microeng.</i> 5 (1995) pp. 115-120.		

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